

SHIGA7.055APC

PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Hirayama et al.  
 Appl. No. : U.S. National Phase of  
               PCT/JP2005/001798  
 Filed : Herewith  
 For : BASE MATERIAL FOR  
       PATTERN-FORMING  
       MATERIAL, POSITIVE RESIST  
       COMPOSITION AND METHOD  
       OF RESIST PATTERN  
       FORMATION  
 Examiner : Unassigned  
 Group Art Unit : Unknown

## CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

August 17, 2006

(Date)

Neil S. Bartfeld, Ph.D., Reg. No. 39,901

PRELIMINARY AMENDMENT

**Mail Stop PCT**  
 Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

Dear Sir:

Prior to examination of the above-referenced application, please enter the following amendments:

**Amendments to the Specification** begin on page 2 of this paper.

**Remarks** begin on page 5 of this paper.